Filing Date: August 31, 2000

CHEMICAL DISPENSING SYSTEM FOR SEMICONDUCTOR WAFER PROCESSING

## IN THE SPECIFICATION

Please amend the specification as follows.

The paragraph beginning at page 1, after the title under "Related Applications" as follows:

This application is a divisional of pending U.S. Application Ser. No. 09/133,989, filed Aug. 14, 1998 and now abandoned; which is a continuation of U.S. Application Ser. No. 08/944,135, filed on October 6, 1997 and issued as U.S. Patent No. 5,952,050; which is a continuation of U.S. Application Ser. No. 08/618,072, filed Feb. 27, 1996 and now abandoned.